DATA SHEET

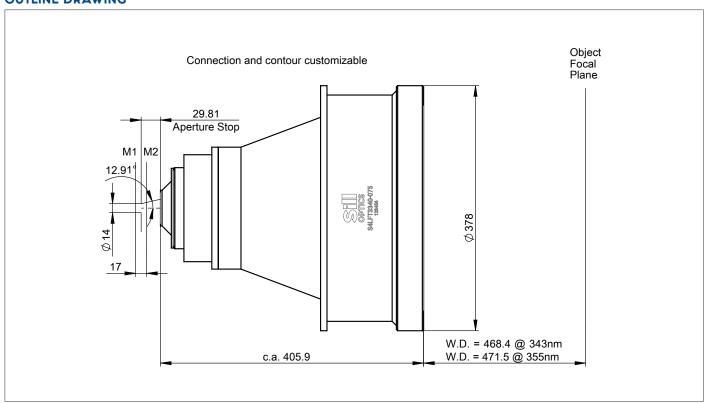
S4LFT3340-075

F-THETA
TELECENTRIC - FUSED SILICA
343, 355 nm



ILLUSTRATION ONLY

OUTLINE DRAWING



All information contained in this data sheet is for information purposes only and is not binding. The content is subject to change at any time without notification, all information without guarantee. We reserve the right to make constructional changes in the course of product improvement. Copyright © Sill Optics GmbH • All rights reserved

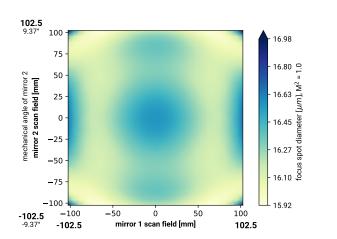


DATA SHEET

SPECIFICATIONS

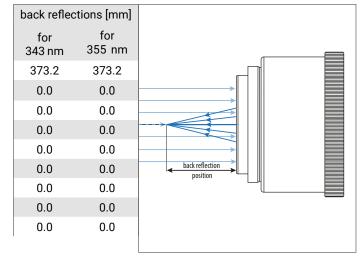
article number	S4LFT33	S4LFT3340-075	
design wavelength [nm]	343	355	
effective focal length [mm]	338.0	340.0	
max. entrance beam-Ø [mm]	14.	14.0	
aperture stop distance [mm]	27.	27.8	
working distance [mm]	468.4	471.5	
scan area for a 2 mirror system with mirror distance from lens housing for	205 x 205		
mirror 2 / mirror 1	21.3 / 38.3		
max. telecentricity error [°]	0.9		
total transmission [%]	> 97		
lens material	fused	fused silica	
LIDT (coating)	1.0 J/cm² per 1ns pulse at 50Hz		
SP and USP usable	ye	yes	
weight [kg]	23.0		
cover glass	S4LPG3340-075		

SPOT FOR 343 nm

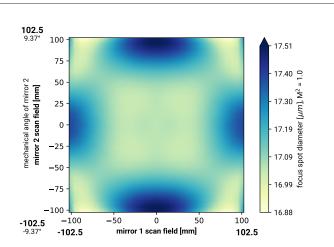


spot diameter at 86.5% level for a Gaussian beam (M² = 1) with 14.0 mm diameter at $1/e^2$, clipped at 14.0 mm field size and mirror distances as given above for a two mirror scan system

BACK REFLECTION POSITION



SPOT FOR 355 nm



spot diameter at 86.5 % level for a Gaussian beam (M² = 1) with 14.0 mm diameter at 1/e², clipped at 14.0 mm field size and mirror distances as given above for a two mirror scan system

REMARKS

The stated values are based on a vignetting of less than 1 %.

Effective focal length and working distance have tolerance of +/- 1.5 %.

Absorption tolerance +/- 25 %. Absorption may increase. Correct cleaning establishes original condition.

All information contained in this data sheet is for information purposes only and is not binding. The content is subject to change at any time without notification, all information without guarantee. We reserve the right to make constructional changes in the course of product improvement. Copyright © Sill Optics GmbH • All rights reserved

